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THE GAERTNER L119 ELLIPSOMETER AND ITS USE  
IN THE MEASUREMENT OF THIN FILMS

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16. ABSTRACT <p>An introduction to the study of ellipsometry is presented, with special attention given to the Gaertner model L119 ellipsometer and the techniques of measuring thin films with this instrument.</p> <p>Values obtained from the ellipsometer are analyzed by a computer program for a determination of optical constants and thickness of the film.</p>			
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## THE GAERTNER L119 ELLIPSOMETER AND ITS USE IN THE MEASUREMENT OF THIN FILMS

### DESCRIPTION

The optical parameters for a thin film present on a reflecting surface may be ascertained by ellipsometry [ 1 ]. Using these values, a computer program based on iterative solutions to the Fresnel equations can calculate the index of refraction, the coefficient of absorption, and the thickness of the film if the index of the reflecting surface and of the ambient medium is known [ 2 ]. The intention of this paper is to discuss ellipsometry and the model L119 Gaertner ellipsometer facility ( Fig. 1 ) which is available in the Thermal Environment Physics Branch of the Space Sciences Laboratory at Marshall Space Flight Center. Interest in this facility has made apparent the desirability of such an explanation.

Ellipsometry deals with the change in the state of the polarization of reflected light [ 3 ]. The ellipsometer measures this change by the orientation of two opposing Glan-Thompson prisms [ 4 ], as shown in Figure 2.

Incident light is plane polarized by an initial Glan-Thompson prism, the polarizer. Its phase is then changed 90 degrees by a  $1/4\lambda$  plate and reflected by the surface under investigation to a second Glan-Thompson prism which analyzes the ellipticity of the reflected light. A photomultiplier increases the sensitivity of the vernier readings for the P and A values [ 3 ].

The light source is a mercury lamp that emits unpolarized light unsuitable for use with the ellipsometer. An interference filter between the light source and the polarizer passes a narrow band [ 546.1 nm ( 5461 Å ) ] of light which is compatible with the compensator. The light is collimated by a series of baffles before encountering the polarizer. The polarizer is able to select a single plane of vibration because its index and coefficient of absorption is different for light polarized in different directions [ 5 ].

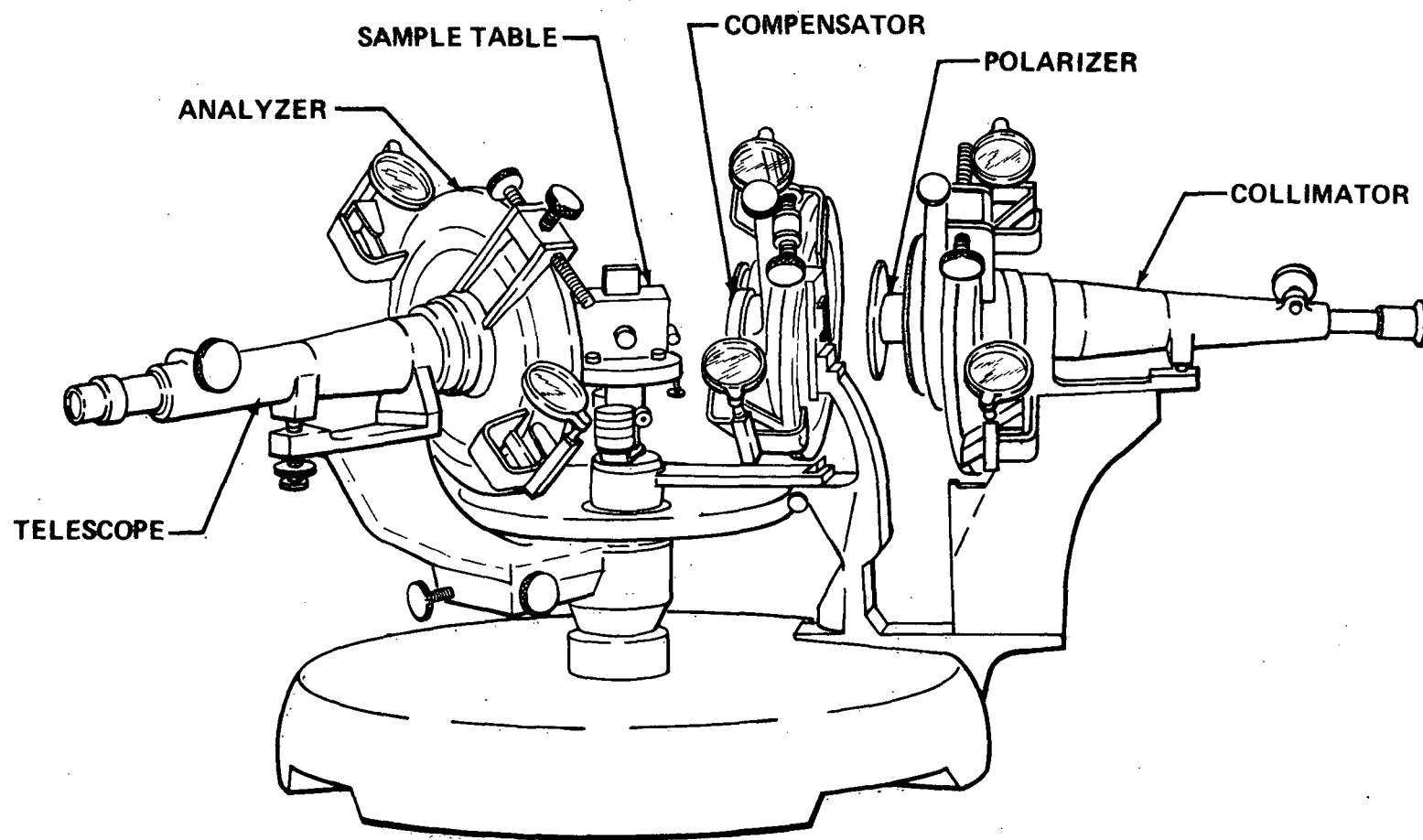


Figure 1. Gaertner ellipsometer L119.

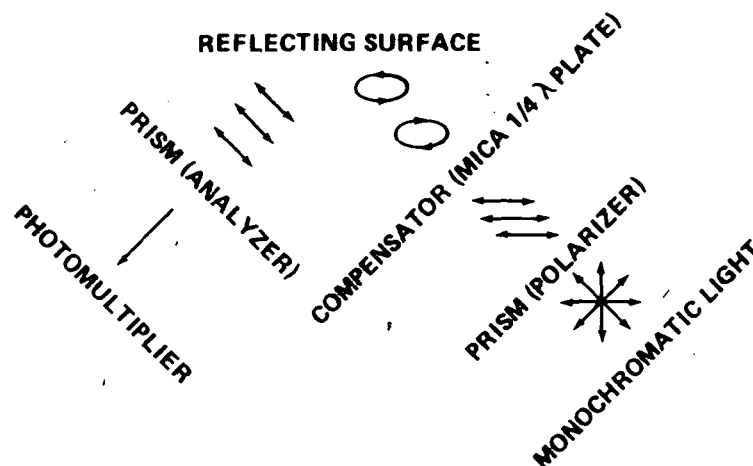


Figure 2. Schematic of the L119 ellipsometer.

A mica  $1/4$ -wave plate standardizes the degree of the polarization of the reflected light by changing the phase of the incident light by 90 degrees, or quarter wavelength [4]. Because the crystallographic and optical axes of mica are complementary, light entering the compensator, except parallel to the axes, will be broken into two new components vibrating parallel to the axes, as shown in Figure 3 [6]. These components will travel at different speeds. One (the ordinary ray) will continue to travel the same distance in the same time as ordinary light. The other component (the extraordinary ray) will travel in the same time a different distance [6]. In this case the distance is the thickness of the mica plate, which for a wavelength of 546.1 nm ( $5461 \text{ \AA}$ ) changes the phase of the light by 90 degrees [1].

A change in phase of 90 degrees constitutes circularly polarized light. This is the state of polarization of the light incident to the surface in question.

Upon reflection, the phase of the light will be further changed because of the reflecting material's index of refraction and its coefficient of absorption [5]. The incident light is again broken into two components, one of which is reflected directly from the surface, while the other is absorbed by the material and then reflected, as shown in Figure 4. As with the compensator, one component of light has traveled farther than the other [3].

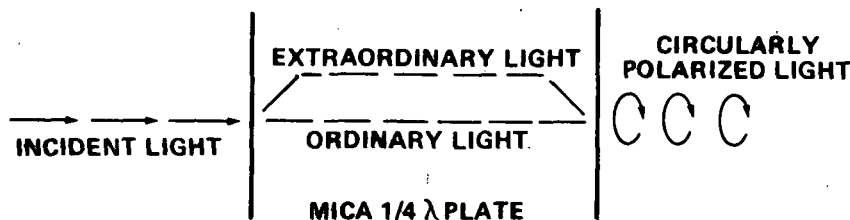


Figure 3. Path of light through mica  $1/4 \lambda$  plate.

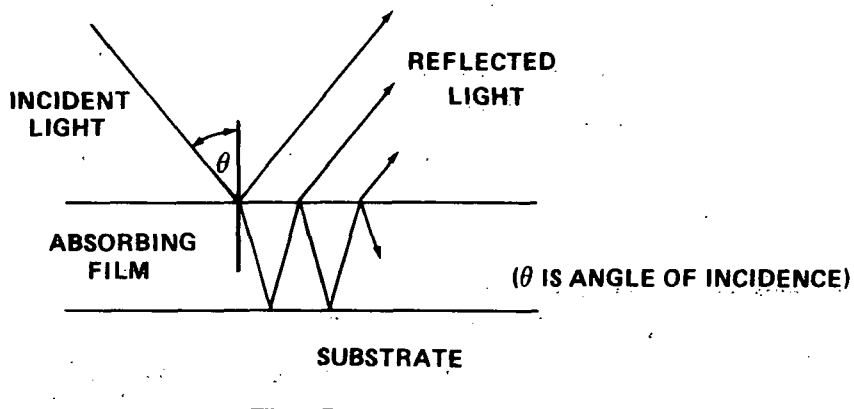


Figure 4. Absorption and reflection of polarized light from a film-covered substrate [ 3 ].

When the light is refocused, its phase will again have been changed; however, the incident light is circularly polarized to compensate for this change in phase by reflection. The electric vectors of the resulting reflected light at any given point along the propagation of the wave will appear to trace an ellipse [ 7 ]. The light can now be analyzed by a second Glan-Thompson prism. This represents the A value. The acuteness of the ellipticity of the light has been compensated for, and the resulting wave is well within the limit of measurement by the analyzer.

After being analyzed, the light is focused into a photomultiplier, enabling the operator to mechanically determine the extinction coefficients of the reflecting surface [ 4 ]. Once the L119 is aligned, the technique for obtaining P and A values is simple. The sample must be mounted securely, insuring proper alignment. Any correction for alignment should be done by the three leveling screws beneath the sample table. The angle of incidence may be set by rotating the telescope until twice the desired angle is read on the vernier beneath the sample table. A Gauss eyepiece inserted in place of the photomultiplier may be used to align and focus the light [ 3 ]. Although a darkened room is not required, it is best that a minimum of room lighting be used. Care should be taken not to expose the photomultiplier to intense light since this will adversely affect it and result in erratic readings.

To obtain a P value, the polarizer vernier should be slowly rotated until the picoammeter shows a minimum or maximum of intensity. This setting may be more accurately read by taking an average of settings that give equal intensities on either side of the minimum [ 3 ]. A reading of the analyzer may be taken in the same way. Only those values in zones 1 (0 to 90 degrees) and 2 (90 to 180 degrees) need to be calculated for use by the computer



program. These values must fall between 0 and 180 degrees, and are designated  $P_1$  and  $P_2$  for the polarizer and  $A_1$  and  $A_2$  for the analyzer. It can be determined that  $P_2 \approx P_1 + 90$  degrees and that  $A_1 + A_2 \approx 180$  degrees [3]. Whether a value appears as a maximum or minimum is of little consequence since any value recorded by one vernier as a maximum may be read again as a minimum, depending on the orientation of the opposing vernier. The accuracy of the L119 may be checked by setting the angle between the telescope and collimator at 180 degrees. If the polarizer is set at 0 or 180 degrees, extinction of the light should occur at 90 or 270 degrees on the analyzer. Some discrepancy has been noted between these ideal extinction settings and those actually occurring with the facility at MSFC. In some instances there are discrepancies of as much as 30 degrees.  $A_1 + A_2$  usually equals from 200 to 215 degrees. This may be caused by improper alignment or any number of varying factors.

Table 1 consists of data taken from a stainless steel mirror and shows the repeatability of the instrument. As shown, the L119 is repeatable within 1 degree. However, repeatability to the nearest 0.01 degree is in the range of this instrument. Again, discrepancies may be caused by misalignment or, more probably, the accuracy with which the operator makes the readings. Nevertheless, the accuracy of the instrument is severely hindered by the unsteadiness of both the collimator and telescope arms. Even after they are locked into position, the arms of the telescope may slip as much as 0.635 centimeters during a reading. As shown in Figure 5, a 10-degree change in the polarizer reading increased the thickness of that particular mirror by almost 8.0 nanometers and a similar change in the analyzer resulted in a difference of 2.0 nanometers.

These values were computed by an 1108 computer using a Fortran program [2]. A change in the polarizer results in a greater change in the computed values than does a similar change in the analyzer. The reason for this is shown in Figure 6. First, note the difference in the shape of the curves for the analyzer and polarizer for the two zones shown. The slope of the A curve is much smoother than the P curve. Changes in A occur over a wider range than do similar changes in P. Also note that a value at  $P_1 + 90$  degrees is approximately equal to the  $P_2$  value at the same angle. However, the  $A_1 + A_2$  value for a given angle in every case greatly exceeds 180 degrees.

Included as Appendix A is a computer output for a program revised from the program mentioned above to run on the 1108 computer facility at MSFC.

TABLE 1. P AND A VALUES FOR ONE ZONE SHOWING REPEATABILITY  
FOR CLEAN STAINLESS STEEL MIRROR

P	A
244.45	16.60
244.30	16.74
244.45	16.60
244.45	16.69
244.42	16.63
244.40	16.69
244.40	16.77
244.30	16.81
244.40	16.82
244.46	16.35
244.55	16.59
244.42	16.57
244.54	16.59
244.56	16.63
244.60	16.59
244.54	16.65
244.55	16.57
244.50	16.60
244.57	16.57
244.60	16.63
244.71	16.70
244.60	16.70
244.65	16.72
244.80	16.68
244.63	16.55
244.43	16.64
244.30	16.59

Appendix B is a graph showing the same type data as shown in Figure 6. It compares a mono-layered aluminum mirror with a multilayered lithium-fluoride on aluminum mirror as a function of their optical parameters and the angle of the incident light.

Shown in Appendix C are the results of the parameters of several mirrors measured as functions of the  $1/4\lambda$  plate and as a function of each other. The calculation of small delta ( $\delta$ ) as used in the fresnel equations for a film on silicon is shown as a function of thickness in Appendix D. Shown in Appendix E is a graph of the same data displaying an elliptical pattern.

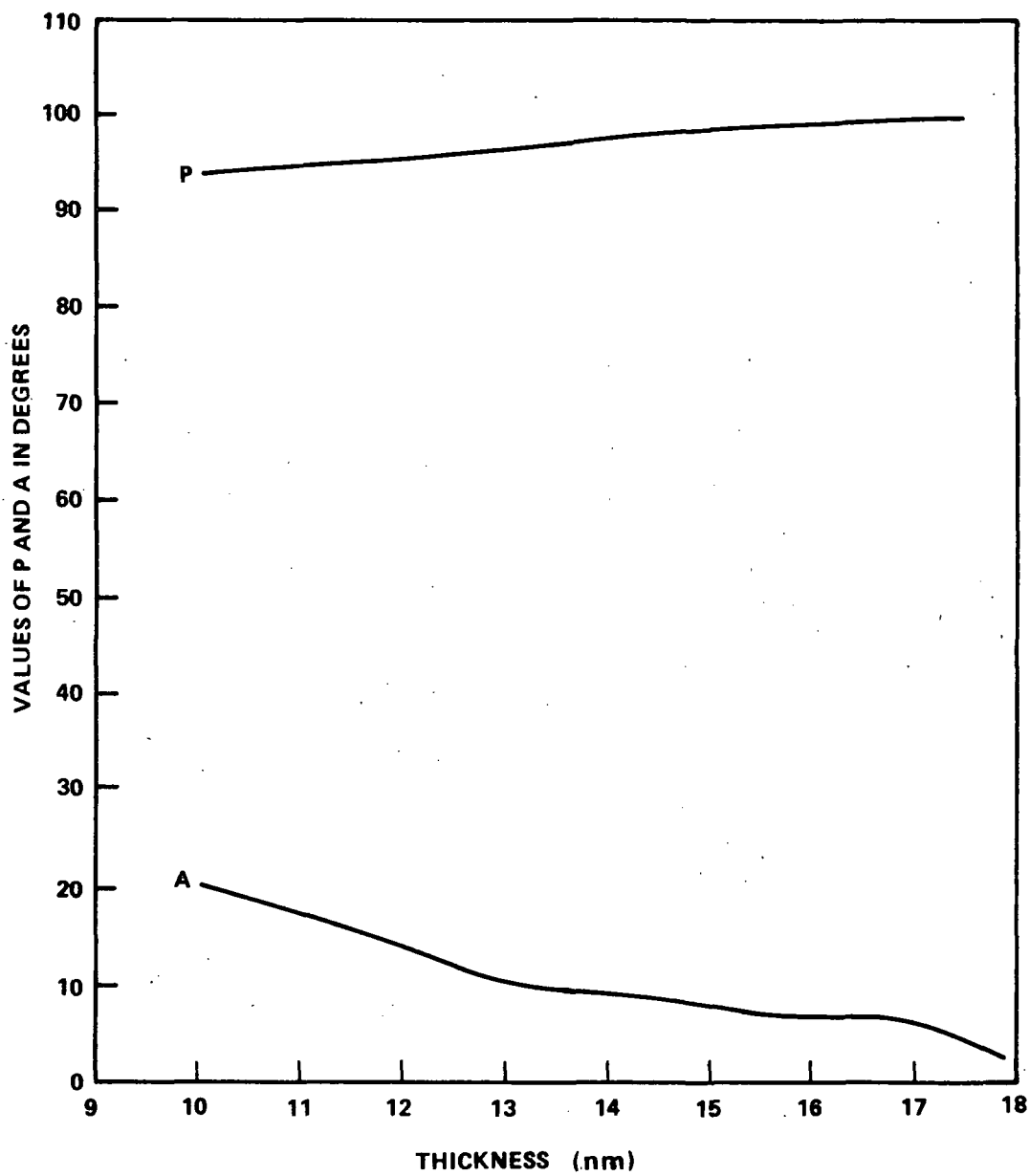


Figure 5. Polarizer and analyzer headings as a function of the thickness of an imaginary film.

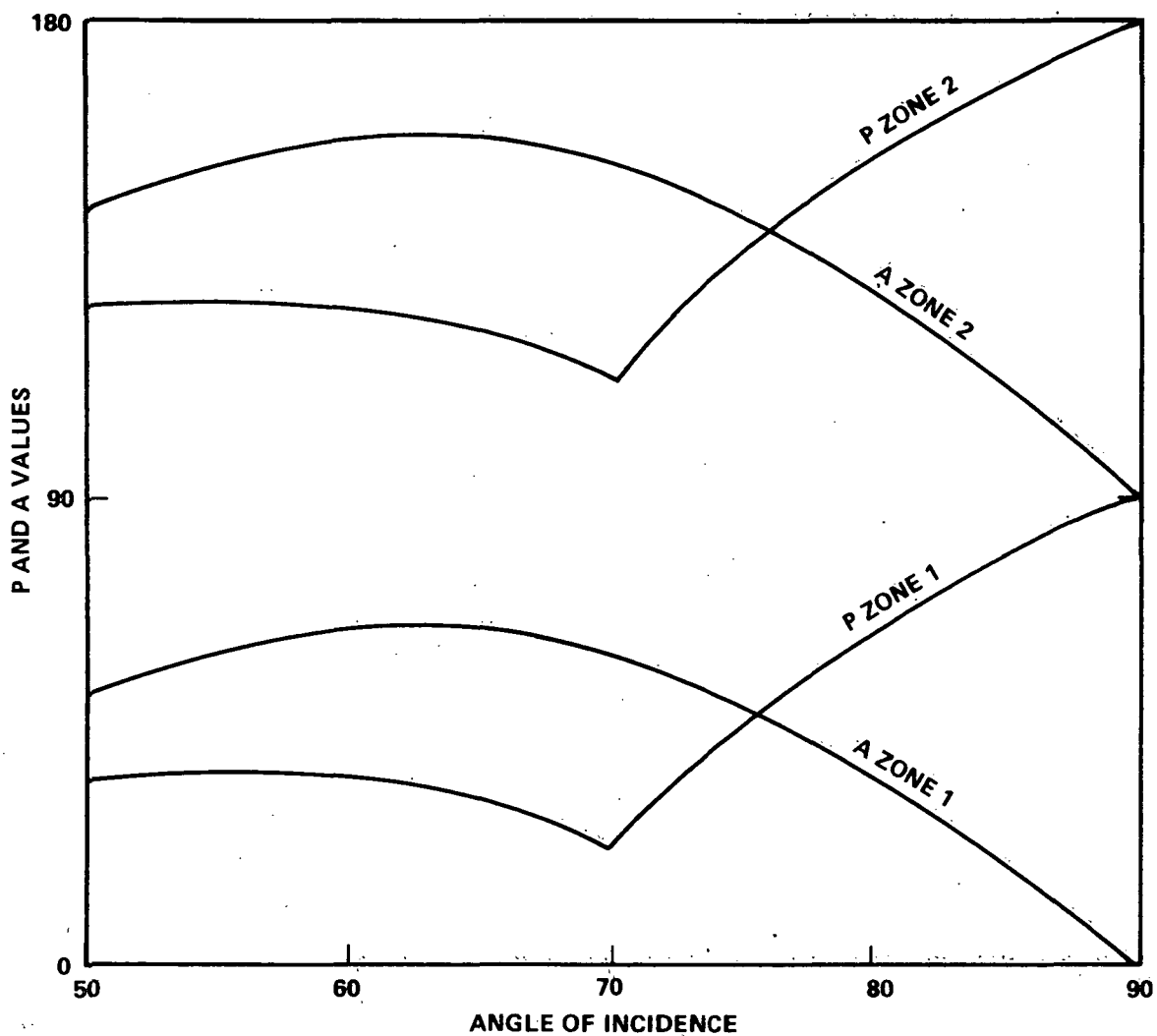


Figure 6. P and A values versus angle of incidence for aluminum mirror.

APPENDIX A  
FORTRAN IV PROGRAM

@ HDG, P  
 @ FOR, IS ELLIPS

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C   CALCULATION FOR ELLIPSOMETER
C   FOR IFILM, THE NUMBER OF FILMS ADD. RESET IS NECESSARY TO ERASE FILMS
C   CHANGED TO USE KAPPA INSTEAD OF IMAGINARY PART OF REFRACTIVE INDEX
    DIMENSION IDT(14),FNSI(2),DFNS(2),FNSE(2),FNSX(2),TN(8),TD(8)
    DIMENSION INST(31)
    COMMON FN1,S1,C1,N,FNX(900),D(900),FN2,CRP,CRN,CRP32,CRN32,WL,
1   RP21,RN21,DEL,PSI,C2,C3,FN2I(2),DFN2(2),FN2E(2),FN2X(2),T1,T2,T3,
2   T4,D2,DELDX,PSIDX, ELDEL,ELPSI,DENP,FNP,DEN1,MX,K,IS
    COMPLEX C2,C3,C1,CIP1,CN,CNM1,CRN,CRN21,CRN32,CRP,CRP21,CRP32
    COMPLEX FN2,FNX,FNS, RHO,RN,RN21, RP,RP21, RC,SRC
    COMPLEX T1,T2,T3,T4,RHOC,RH01,RH02,CAT,ALP1,ALP2,BET1,BET2
    COMPLEX GAM1,GAM2,CAT
C   INSTRUCTIONS TO BE COMPARED WITH INSTRUCTIONS GIVEN WITH
C   DATA
C   M=      1      2      3      4      5      6
C   DATA INST/6HPAGE ,6HNM ,6HNF ,6HNS ,6HAI ,6HWL ,
C   7      8      9      10     11     12     13
1   6HWP ,6HNREF ,6HEDP ,6HELOP ,6HRESET ,6HFILM ,6HMXED ,
C   14     15     16     17     18     19     20
2   6HCTABLE,6HCD ,6HCND ,6HCNDE ,6HCNDC ,6HCNS ,6HCWP ,
C   21     22     23     24     25     26     27
3   6HCDN ,6HCDNE ,6HCDNC ,6HAT ,6HCAT ,6HCATA ,6HIFILM ,
C   28     29     30     31
4   6HALINE ,6HSTOP ,2HFT,3HCNK/
C   SRC IS SMALL REFLECTION COEFFICIENT (WITHOUT CONSIDERING
C   UNDERLYING LAYERS)
    SRC(A,B)=(A-B)/(A+B)
C   SIN,COS,ATAN,TAN FOR ANGLES IN DEGREES
    SIND (X)=SIN(X/57.29578)
    COSD (X)=COS(X/57.29578)
    ATAND (X)=ATAN(X)*57.29578
    TAND(X)=SIND(X)/COSD(X)
C   S IS USED FOR CALCULATING SPECIFIC REFRACTION
    S(XN)=(XN*XN-1.)/(XN*XN+2.)
C   GIVE STANDARD VALUES TO VARIABLES
10  FN1I=1.
    DFN1=0.
    FN1E=0.
    AT=0.
    ALP=0.
    ALA=0.
    ALQ=0.
    FN2I(1)=1.
    FN2I(2)=0.
    DFN2(1)=0.
    DFN2(2)=0.
    FN2E(1)=0.
    FN2E(2)=0.
    FNSI(1)=1.
    FNSI(2)=0.
    DFNS(1)=0.
    DFNS(2)=0.
    FNSE(1)=0.
    FNSE(2)=0.
    AII=70.
    AIE=0.
    WLI=5461.
  
```

```

DWL=0.
WLE=0.
RHOC=(0.,-1.)
TC=1.
DELC=90.
DEN1=1.
DENP=1.
FNP=1.5
N=2
ELDEL=.002
ELPS1=.002
D2I=0.
DD2=0.
D2F=0.
FN=1.
EDEL=.015
EPSI=.015
C      READ AND PRINT TITLE CARD
12 READ(5,15) IDT
15 FORMAT(13A6,A2)
WRITE(6,17) IDT
17 FORMAT(1H1,14A6)
C      READ AND PRINT CARD OF DATA
20 READ(5,25) L,Z1,Z2,Z3,Z4,Z5,Z6
25 FORMAT(A6,3X,6F10.0)
WRITE(6,27) L,Z1,Z2,Z3,Z4,Z5,Z6
27 FORMAT(1H ,A6,3X,6F15.5)
C      COMPARE L WITH INSTRUCTIONS TO FIND M.
DO 30 M=1,31
30 IF(L.EQ.INST(M)) GO TO 35
GO TO 20
C      M= 1 2 3 4 5 6 7 8 9 10 11 12 13 14 15 16
35 GO TO(12,50,70,80,90,100,110,120,130,140,10,150,160,305,170,170,
C      17 18 19 20 21 22 23 24 25 26 27 28 29 30 31
1 170,170,170,730,170,170,170,250,750,750,270,260,810,305,170),M
C      INSTRUCTION NM, REFRACTIVE INDEX OF MEDIUM
50 FN1I=Z1
DFN1=Z2
FN1E=1.000001*Z3
GO TO 20
C      INSTRUCTION NF, REFRACTIVE INDEX OF TOP FILM
70 FN2I(1)=Z1
DFN2(1)=Z2
FN2E(1)=1.000001*Z3
FN2I(2)=Z4
DFN2(2)=Z5
FN2E(2)=1.000001*Z6
C      IF DFN2(1) IS LEFT BLANK ON DATA CARD, SUBSTITUTE A VALUE OF
C      DFN2(1) SO THAT ONLY ONE CALCULATION WILL BE PERFORMED.
IF(ABS(DFN2(1)).EQ.0.) DFN2(1)=1.000002*ABS(FN2E(1)-FN2I(1))
C      INSTRUCTION NS, REFRACTIVE INDEX OF SUBSTRATE
80 FNSI(1)=Z1
DFNS(1)=Z2
FNSE(1)=1.000001*Z3
FNSI(2)=Z4
DFNS(2)=Z5
FNSE(2)=1.000001*Z6
GO TO 20
C      INSTRUCTION AI, ANGLE OF INCIDENCE
90 AII=Z1
DAI=Z2
AIE=1.000001*Z3

```

```

      GO TO 20
C      INSTRUCTION WL, WAVE LENGTH OF LIGHT
100 WLI=Z1
      DWL=Z2
      WLE=1.000001*Z3
      GO TO 20
C      INSTRUCTION WP, CONSTANTS OF WAVE PLATE
110 TC=Z1
      DELC=Z2
      RHOC=TC*CEXP((0.,-1.)*DELC/57.29578)
      GO TO 20
C      INSTRUCTION NREF, NUMBER OF REFLECTIONS OF THE LIGHT
120 FN=Z1
      GO TO 20
C      INSTRUCTION EDP, CONFIDENCE LIMITS FOR DELTA AND PSI
130 EDEL=Z1
      EPSI=Z2
      GO TO 20
C      INSTRUCTION ELDP, ERROR LIMITS FOR DELTA AND PSI
140 ELDEL=Z1
      ELPSI=Z2
      GO TO 20
C      INSTRUCTION FILM, NUMBER, THICKNESS AND REFRACTIVE INDEX OF FILM
150 I=1.000001*Z1+1
      D(I)=Z2
      FNX(I)=CMPLX(Z3,-Z3*ABS(Z4))
      N=MAX0(N,I)
      GO TO 20
C      INSTRUCTION MIXED, DATA FOR MIXED FILMS
160 DEN1=Z1
      DENP=Z2
      FNP=Z3
      GO TO 20
C      VALUES OF DELTA AND PSI OR OF P,A, AND Q HAVE BEEN GIVEN
C      USE PREVIOUS VALUES OF DEL AND PSI IF NO DATA IS GIVEN, Z1=Z2=0
C      IF FIRST VALUE(Z1) =0, USE PREVIOUSLY GIVEN VALUES OF
C      DELTA AND PSI
170 IF(ABS(Z1).EQ.0.) GO TO 310
      IF(ABS(Z5).EQ.0.) GO TO 180
C      Z5 NOT =0, SO P1,A1,P2,A2,Q ARE GIVEN
C      COMPUTE TWO VALUES OF RHO
      Z1=Z1+AT+ALP
      Z2=Z2+AT+ALA
      Z3=Z3+AT+ALP
      Z4=Z4+AT+ALA
      Z5=Z5+AT+ALQ
      WRITE(6,27) L,Z1,Z2,Z3,Z4,Z5
174 RH01=TAND(Z2)*((TAND(Z5)+TAND(Z1-Z5)*RHOC)/(TAND(Z1-Z5)*TAND(Z5)*
1      RHOC-1.)
      RH02=TAND(Z4)*((TAND(Z5)+TAND(Z3-Z5)*RHOC)/(TAND(Z3-Z5)*TAND(Z5)*
1      RHOC-1.)
EC      AVERAGE VALUES OF RHO, COMPUTE VALUES OF DELTA AND PSI
      RH0=(RH01+RH02)/2.
      DEL1=ATAN2(AIMAG(RH01),REAL(RH01))*57.29578
      PSI1=ATAN2(CABS(RH01))
      DEL2=ATAN2(AIMAG(RH02),REAL(RH02))*57.29578
      PSI2=ATAN2(CABS(RH02))
      WRITE(6,175) DEL1,PSI1,DEL2,PSI2
175 FORMAT(6H DEL1=,F12.6,6H PSI1=,F12.6,6H DEL2=,F12.6,
1 6H PSI2=,F12.6)
      IF(FN.EQ.1.) GO TO 210
      GO TO 200

```



```

C      IF Z3=0, DELTA AND PSI ARE GIVEN, OTHERWISE P,A,Q ARE GIVEN
180 IF(ABS(Z3).EQ.0.) GO TO 190
      Z1=Z1+AT+ALP
      Z2=Z2+AT+ALA
      Z3=Z3+AT+ALQ
      WRITE(6,27) L,Z1,Z2,Z3
185 RHO=TAND(Z2)*(TAND(Z3)+TAND(Z1-Z3)*RHOC)/(TAND(Z1-Z3)+TAND(Z3)*
1      RHOC-1.)
      IF(FN.EQ.1.) GO TO 210
      GO TO 200
190 DEL=Z1
      PSI=Z2
      RHO=TAND(PSI)*CEXP((0.,1.)*DEL/57.29578)
      IF(FN.EQ.1.) GO TO 310
C      CORRECT FOR NUMBER OF REFLECTIONS IF FN NOT =1
200 RHO=CEXP(1./FN*CLOG(RHO))
210 DEL=ATAN2(AIMAG(RHO),REAL(RHO))*57.29578
      PSI=ATAND(CABS(RHO))
      IF(M.EQ.25 .OR. M.EQ.26) GO TO 755
215 WRITE(6,220) DEL,PSI
220 FORMAT(6H DEL=,F13.6,5H PSI=,F13.6)
      GO TO 310
C      INSTRUCTION AT, ANGLE OF TILT OF SAMPLE
250 AT=Z1
      GO TO 20
C      INSTRUCTION ALINE, ALINEMENT CORRECTIONS
260 ALP=Z1
      ALA=Z2
      ALQ=Z3
      GO TO 20
C      INSTRUCTION IFILM, CALCULATES THICKNESSES AND REFRACTIVE
C      INDICES OF A SERIES OF FILMS
270 XNF=Z1
      TH=Z2
C      REMOVE ALL PREVIOUSLY DESIGNATED FILMS.
C      WITHOUT NEXT CARD, FILMS WILL BE PLACED BETWEEN PREVIOUSLY
C      DESIGNATED FILMS AND SUBSTRATE
      N=2
C      DN AND DK ARE INCREMENTS OF REFRACTIVE INDEX AND K
      DN=(Z5-Z3)/XNF
      DK=(Z6-Z4)/XNF
C      COMPUTE INDEX AND K (KAPPA) OF TOP FILM
      Z3=Z3+DN/2.
      Z4=Z4+DK/2.
C      INDEX OF TOP FILM IS N1, INDEX OF BOTTOM FILM IS N
      N1=N+1
      NF=1.000001*XNF
      N=N+NF
      DO 280 I=N1,N
      D(I)=TH/NF
      FN(I)=CMPLX(Z3,-Z3*Z4)
      Z3=Z3+DN
280 Z4=Z4+DK
      GO TO 20
C      THICKNESS OF TOP FILM AND ,OPTIONALLLY, SETTING OF WAVE PLATE
305 D2I=Z1
      D2E=Z2
      D2E=1.000001*Z3
      Q=Z4
      IF(M.EQ.30) GO TO 20
C      SET INITIAL VALUES
310 FN1=FN1I

```

```

311 AI=AI1
312 S1=SIND(AI)
    C1=COSD(AI)
    IF(M.EQ.19) GO TO 710
315 WL=WLI
    WRITE (6,316) FN1,AI,WL,TC,DELC
316 FORMAT(17H0INDEX OF MEDIUM=,F10.5,21H ANGLE OF INCIDENCE=,F10.3,
1 14H WAVE LENGTH=,F10.2,5H TC=,F10.5,7H DELC=,F10.3)
    IF(M.EQ.14) GO TO 320
    IF(M.EQ.31) GO TO 318
C      PRINT TABLE HEADINGS EXCEPT FOR CTABLE OR CNK
    WRITE(6,317)
317 FORMAT(123H0 THICK NF REAL KAPPA ADSORPTION D DEL D P
1SI ERROR NF-NM NS-NF WT FRACTION NS REAL KAPPA
2 K)
    GO TO 320
C      PRINT HEADINGS FOR INSTRUCTION CNK
318 PRINT 319
319 FORMAT(1H0,8X,2HNF,15X,5HKAPPA,9X,4HD NF,11X,7HD KAPPA,9X,
1 5HERROR,3X,7HD DELTA,5X,5HD PSI,10X,5HTHICK)
320 NP1=N+1
C      SET VALUES FOR REFRACTIVE INDEX OF SUBSTRATE
325 FNSX(1)=FNSI(1)
326 FNSX(2)=FNSI(2)
327 FNX(NP1)=CMPLX(FNSX(1),-FNSX(2)*FNSX(1))
C      COMPUTE REFLECTION COEF BETWEEN LAYERS 3 AND 4
    IF(N.EQ.2) GO TO 335
    X=SIND(AI)*FN1
    CN=CSQRT(1.-(X/FNX(N+1))**2)
    CNM1=CSQRT(1.-(X/FNX(N))**2)
    CRP=SRC(FNX(N+1)*CNM1,FNX(N)*CN)
    CRN=SRC(FNX(N)*CNM1,FNX(N+1)*CN)
    IF(N.EQ.3) GO TO 335
    NX=N-3
    I=N-1
    DO 330 J=1,NX
        CIP1=CSQRT(1.-(X/FNX(I+1))**2)
        CI= CSQRT(1.-(X/FNX(I)) **2)
        RP=SRC(FNX(I+1)*CI,FNX(I)*CIP1)
        RN=SRC(FNX(I)*CI,FNX(I+1)*CIP1)
        T1=FNX(I+1)*CIP1*D(I+1)/WL
        CRP=RC(RP,CRP,T1)
        CRN=RC(RN,CRN,T1)
330 I=I-1
335 IF(M.EQ.31) GO TO 850
340 FN2X(2)=FN2I(2)
342 FN2X(1)=FN2I(1)
343 FN2=CMPLX(FN2X(1),-FN2X(2)*FN2X(1))
C      CALCULATE REFLECTION COEF BETWEEN LAYERS 2 AND 3
    CALL CRC
    IF(M.EQ.14) GO TO 350
    K=1
C      EXCEPT FOR CTABLE,CALCULATE VALUES,T1 AND T2, OF FILM
C      THICKNESS
    CALL CALDX (T1,T2)
    IF(M.EQ.15) GO TO 455
C      EXCEPT FOR CTABLE OR CD,CALCULATE COMPLEX VALUES T3 AND
C      T4 OF FILM THICKNESS FOR UPPER VALUE OF FILM
C      REFRACTIVE INDEX
    FN2=CMPLX(FN2X(1)+DFN2(1),-FN2X(2)*(FN2X(1)+DFN2(1)))
    CALL CRC
    CALL CALDX(T3,T4)

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C   IS=1 FOR NO SOLUTION FOUND  IS=2 FOR SOLUTION FOUND
    IS=1
    IF(( AIMAG(T1).GT.0..AND.AIMAG(T3).LT.0.).OR.(AIMAG(T1).LT.0..AND.
      1 AIMAG(T3).GT.0.)) GO TO 485
C   NO SOLUTION FOR N2 FOR FIRST SOLUTION OF QUADRATIC
345 IF((AIMAG(T2).GT.0..AND.AIMAG(T4).LT.0.).OR.(AIMAG(T2).LT.0..AND.
      1 AIMAG(T4).GT.0.)) GO TO 487
C   NO SOLUTION FOR N2 FOR SECOND SOLUTION OF QUADRATIC
347 IF(1S.EQ.2) GO TO 670
C   NO SOLUTION FOUND, TRY OTHER QUADRANTS FOR SQRT IN CALDX
    K=3
    FN2=CMPLX(FN2X(1),-FN2X(2)*FN2X(1))
    CALL CRC
    CALL CALDX (T1,T2)
    FN2=CMPLX(FN2X(1)+DFN2(1),-FN2X(2)*(FN2X(1)+DFN2(1)))
    CALL CRC
    CALL CALDX(T3,T4)
    IF(( AIMAG(T1).GT.0..AND.AIMAG(T3).LT.0.).OR.(AIMAG(T1).LT.0..AND.
      1 AIMAG(T3).GT.0.)) GO TO 490
348 IF((AIMAG(T2).GT.0..AND.AIMAG(T4).LT.0.).OR.(AIMAG(T2).LT.0..AND.
      1 AIMAG(T4).GT.0.)) GO TO 489
    GO TO 670
C   TABLES OF DEL AND PSI FOR CTABLE
350 WRITE(6,360)
360 FORMAT(1H0,3X,5HTHICK,4X,3HDEL,5X,3HPSI,4X,14HRF.CF.PARALLEL,6X,
      1 12HRF.CF.NORMAL,4X,2HNF,4X,5HKAPPA,2X,2HNS,5X,5HKAPPA,4H,
      2 2HP1,5X,2HA1,5X,2HP2,5X,2HA2)
390 D2=D2I
400 CRP21=RC(RP21,CRP32,FN2*C2*D2/WL)
    CRN21=RC(RN21,CRN32,FN2*C2*D2/WL)
    RHO=CRP21/CRN21
    IF(FN.NE.1.) RHO=CEXP(1./FN*CLOG(RHO))
    DEL=ATAN2(AIMAG(RHO),REAL(RHO))*57.29578
    IF(REAL(RHO).LT.0. .AND. ABS(AIMAG(RHO)).LT. 1.0E-6) DEL=180.
    PSI=ATAND(CABS(RHO))
    XM1=CABS(CRP21)
    THETA1=ATAN2(AIMAG(CRP21),REAL(CRP21))*57.29578
    IF(REAL(CRP21).LT.0. .AND. ABS(AIMAG(CRP21)).LT.1.0E-6) THETA1=180.
    XM2=CABS(CRN21)
    THETA2=ATAN2(AIMAG(CRN21),REAL(CRN21))*57.29578
    IF(REAL(CRN21).LT.0. .AND. ABS(AIMAG(CRN21)).LT.1.0E-6) THETA2=180.
    FN2R=REAL(FN2)
    FNXR=REAL(FNX(N+1))
    FK2=-AIMAG(FN2)/REAL(FN2)
    FKX=-AIMAG(FNX(N+1))/REAL(FNX(N+1))
    IF(ABS(Q).NE.0.) GO TO 420
    WRITE(6,410) D2,DEL,PS1,XM1,THETA1,XM2,THETA2,FN2R,FK2,FNXR,FKX
410 FORMAT(1H F8.1,2F8.3,2(F9.5,F9.3),4F7.4,4F7.2)
    GO TO 450
C   Q NOT 0, COMPUTE P AND A READINGS FOR VALUE OF Q
C   CORRECT Q FOR TILT AND ALINEMENT.
420 TQ=TAND(Q+AT+ALQ)
    IF(ABS(DEL).LT.1.0E-6) GO TO 430
    R=(TQ*SIND(DEL-DELC)-SIND(DEL+DELC)/TQ)/2./SIND(DEL)
    TP1=(-R+SQRT(R*R+1))/TC
    TP2=(-R-SQRT(R*R+1))/TC
    P1=ATAND(TP1)+Q-ALP+ALQ
    P2=ATAND(TP2)+Q-ALP+ALQ
    A1=ATAND(REAL(RHO*(TP1*TQ*RHOC-1.))/(TQ+TP1*RHOC))-AT-ALA
    A2=ATAND(REAL(RHO*(TP2*TQ*RHOC-1.))/(TQ+TP2*RHOC))-AT-ALA
    GO TO 440
C   USE LIMITING FORMS OF EQUATIONS FOR DEL NEARLY =0.

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430 P1=Q-ALP*ALQ
    P2=Q-ALP*ALQ-90.
    A1=ATAND(REAL(RHO/TQ))-AT-ALA
    A2=ATAND(REAL(RHO*TG))-AT-ALA
C   REDUCE ANGLES TO LIE BETWEEN 0 AND 180 DEGREES
440 P1=AMOD(P1+360.,180.)
    A1=AMOD(A1+360.,180.)
    P2=AMOD(P2+360.,180.)
    A2=AMOD(A2+360.,180.)
    WRITE(6,410) D2,DEL,PSI,XM1,THETA1,XM2,THETA2,FN2R,FK2,FNXR,
1   FKX,P1,A1,P2,A2
450 D2=D2+DD2
    IF(D2.LT.D2E) GO TO 400
    GO TO 670
C   COMPUTE FILM THICKNESS M=15      CD
C   PICK THICKNESS WITH SMALLEST IMAGINARY PART
455 IF(ABS(AIMAG(T2)).LT.ABS(AIMAG(T1))) GO TO 460
    D2=REAL(T1)
    ERROR=AIMAG(T1)
    K=1
    GO TO 470
460 D2=REAL(T2)
    ERROR=AIMAG(T2)
    K=2
C   COMPUTE DEL AND PSI FOR CALCULATED FILM THICKNESS D2
470 CRP21=RC(RP21,CRP32,FN2*C2*D2/WL)
    CRN21=RC(RN21,CRN32,FN2*C2*D2/WL)
    RH01=CRP21/CRN21
    PSIX=ATAND(CABS(RH01))-PSI
    DELX=57.29578*ATAN2(AIMAG(RH01),REAL(RH01))-DEL
    DIFN21=REAL(FN2)-FN1
    DIFN32=REAL(FNX(N+1))-REAL(FN2)
C   WEIGHT FRACTION AND WEIGHT OF MATERIAL IN UNIT AREA OF FILM
    FRACN=DENP/(DENP+(S(REAL(FN2))-S(FNP))*DEN1/(S(FN1)-S(REAL(FN2))))
1   )
    WTMT=1.0E-5*D2*FRACN/(FRACN/DENP+(1.-FRACN)/DEN1)
    FN2R=REAL(FN2)
    FNXR=REAL(FNX(N+1))
    FK2=-AIMAG(FN2)/REAL(FN2)
    FKX=-AIMAG(FNX(N+1))/REAL(FNX(N+1))
    WRITE(6,480) D2,FN2R,FK2,WTMT,DELX,PSIX,ERROR,DIFN21,DIFN32,
1   FRACN,FNXR,FKX,K
480 FORMAT(1H ,F8.1,2F9.5,1PE12.4,0P2F9.3,F12.5,3F10.5,2F9.5,I6)
    GO TO 670
C   CALCULATE SOLUTION FOR N2 FOR FIRST SOLUTION OF QUADRATIC
485 K=1
    GO TO 490
487 K=2
    GO TO 490
489 K=4
C   MX=16 SO THAT SOLN2 WILL PRINT
490 MX=16
    CALL SOLN2
    MX=M
    IF(M.EQ.16 .OR. M.EQ.21 .OR. IS.EQ.1) GO TO (345,347,348,670),K
C   PRINT BLANK SPACE
    WRITE(6,27)
C   CALCULATE ERROR LIMITS FOR N2 AND D2
    DEL0=DEL
    PSI0=PSI
    DEL=DEL0+1.249*EDEL
    CALL SOLN2

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TN(1)=REAL(FN2)
TD(1)=D2
DEL=DEL0-1.249*EDEL
CALL SOLN2
TN(2)=REAL(FN2)
TD(2)=D2
DEL=DEL0
PSI=PSI0+1.249*EPSI
CALL SOLN2
TN(3)=REAL(FN2)
TD(3)=D2
PSI=PSI0-1.249*EPSI
CALL SOLN2
TN(4)=REAL(FN2)
TD(4)=D2
DEL=DEL0+0.883*EDEL
PSI=PSI0+0.883*EPSI
CALL SOLN2
TN(5)=REAL(FN2)
TD(5)=D2
DEL=DEL0-0.883*EDEL
CALL SOLN2
TN(6)=REAL(FN2)
TD(6)=D2
DEL=DEL0+0.883*EDEL
PSI=PSI0-0.883*EPSI
CALL SOLN2
TN(7)=REAL(FN2)
TD(7)=D2
DEL=DEL0-0.883*EDEL
CALL SOLN2
TN(8)=REAL(FN2)
TD(8)=D2
FN2MIN=AMIN1(TN(1),TN(2),TN(3),TN(4),TN(5),TN(6),TN(7),TN(8))
FN2MAX=AMAX1(TN(1),TN(2),TN(3),TN(4),TN(5),TN(6),TN(7),TN(8))
D2MIN=AMIN1(TD(1),TD(2),TD(3),TD(4),TD(5),TD(6),TD(7),TD(8))
D2MAX=AMAX1(TD(1),TD(2),TD(3),TD(4),TD(5),TD(6),TD(7),TD(8))
WRITE(6,495) D2MIN,D2MAX,FN2MIN,FN2MAX
495 FORMAT(39H0CONFIDENCE LIMITS OF FILM THICKNESS ISF8.1,3H TOF8.1/
1      69H CONFIDENCE LIMITS OF THE REAL PART OF INDEX OF REFRACTI
20N OF FILM ISF12.5,3H TO F12.5)
GO TO (345,347,348,670),K
670 FN2X(1)=FN2X(1)+DFN2(1)
IF(FN2X(1).LT.FN2E(1)) GO TO 343
700 FN2X(2)=FN2X(2)+DFN2(2)
IF(FN2X(2).LT.FN2E(2)) GO TO 342
FNSX(2)=FNSX(2)+DFNS(2)
IF(FNSX(2).LT.FNSE(2)) GO TO 327
FNSX(1)=FNSX(1)+DFNS(1)
IF(FNSX(1).LT.FNSE(1)) GO TO 326
WL=WL+D*L
IF(WL.LT.WLE) GO TO 320
705 AI=AI+DAI
IF(AI.LT.AIE) GO TO 312
FN1=FN1+DFN1
IF(FN1.LT.FN1E) GO TO 311
GO TO 20
C      CALCULATE REFRACTIVE INDEX OF SUBSTRATE CNS
710 FNS=FN1*S1/C1*CSQRT(1.-4.*RHO*S1**2/(RHO+1.)**2)
FNSI(1)=REAL(FNS)
FNSI(2)=-AIMAG(FNS)/FNSI(1)
FNSE(1)=0.

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      FNSE(2)=0.
      WRITE(6,720) FNSI,DEL,PSI
720  FORMAT(20H0INDEX OF SUBSTRATE=F9.4,F9.4,2H ,2X,4HDEL=,
1    F9.3,2X,4HPSI=F9.3)
      IF(FNSI(2).LT.0.) GO TO 725
      GO TO 705
725  WRITE(6,727)
727  FORMAT(62H0KAPPA IS SET EQUAL TO 0.SINCE A NEGATIVE VALUE WAS CALC
      ULATED)
      FNSI(2)=0.
      GO TO 705
C      COMPUTE CONSTANTS OF WAVE PLATE          CWP
C      ASSUMES ANGLE OF TILT AT IS ZERO
730  Z1=Z1+ALP
      Z2=Z2+ALA
      Z3=Z3+ALP
      Z4=Z4+ALA
      Z5=Z5+ALQ
      WRITE(6,27) L,Z1,Z2,Z3,Z4,Z5
      IF(ABS(Z3-Z5).LT.0.1 .OR. ABS(Z1-Z5).LT.0.1) GO TO 745
735  B=(TAND(Z2)*(TAND(Z3-Z5)*TAND(Z5)-TAND(Z1-Z5)/TAND(Z5))-TAND(Z4)*
1    (TAND(Z1-Z5)*TAND(Z5)-TAND(Z3-Z5)/TAND(Z5)))/2./
2    (TAND(Z2)-TAND(Z4))
      DELC= ATAN2(SQRT(-B*B-TAND(Z1-Z5)*TAND(Z3-Z5)),B)*57.29578
      TC=1./SQRT(-TAND(Z1-Z5)*TAND(Z3-Z5))
      RHOC=TC*CEXP((0.,-1.)*DELC/57.29578)
      RHO =TAND(Z2)*(TAND(Z5)+TAND(Z1-Z5)*RHOC)/(TAND(Z1-Z5)*TAND(Z5)*
1    RHOC-1.)
      DEL=57.29578*ATAN2(AIMAG(RHO),REAL(RHO))
      PSI=ATAN2(CABS(RHO))
      WRITE(6,740) TC,DELC,DEL,PSI
740  FORMAT(4H TC=,F10.5,9H DELTA C=,F10.5,7H DELTA=,F15.5,5H PSI=,
1    F15.5)
      GO TO 20
745  WRITE (6,747)
747  FORMAT( 73H0CONSTANTS OF WAVE PLATE CAN NOT BE ACCURATELY CALCULAT
      IED FROM ABOVE DATA)
      GO TO 20
C      CALCULATE ANGLE OF TILT OF STAGE ON ELLIPSOMETER CAT IS COMP
C      ANGLE WITH REAL PART ANGLE AND IMAGINARY PART ERROR
750  Z1=Z1+ALP
      Z2=Z2+ALA
      Z3=Z3+ALP
      Z4=Z4+ALA
      Z5=Z5+ALQ
      WRITE(6,27 ) L,Z1,Z2,Z3,Z4,Z5
      TP1=TAND(Z1-Z5)
      TA1=TAND(Z2)
      TP2=TAND(Z3-Z5)
      TA2=TAND(Z4)
      TQ =TAND(Z5)
      ALP1=TA1*(TQ+TP1*RHOC)
      ALP2=TA2*(TQ+TP2*RHOC)
      GAM1=TP1*TQ*RHOC-1.
      GAM2=TP2*TQ*RHOC-1.
      BET1=ALP1/SIND(Z2)/COSD(Z2)+((TA1-ALP1*TP1*RHOC/GAM1)/COSD(Z5))**2
      BET2=ALP2/SIND(Z4)/COSD(Z4)+((TA2-ALP2*TP2*RHOC/GAM2)/COSD(Z5))**2
      CAT=(ALP2*GAM1-ALP1*GAM2)/(BET1*GAM2-BET2*GAM1)*57.29578
      ATX=REAL(CAT)
      Z1=Z1+ATX
      Z2=Z2+ATX
      Z3=Z3+ATX

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      Z4=Z4+ATX
      Z5=Z5+ATX
C      COMPUTE RHO,DEL,PSI
      GO TO 174
755 PRINT 760,CAT,DEL,PSI
760 FORMAT(15H ANGLE OF TILT=,F13.5,15H DEGREES,ERROR=,F13.5,
1       7H DELTA=,F15.5,5H PSI=,F15.5)
      IF(M.EQ.26) ATX=(ATX+AT)/2.
      AT=ATX
      GO TO 20
810 STOP
C INSTRUCTION CNK M=31 COMPUTES N AND KAPPA OF FILM
850 D2=D21
852 PRINT 855,D2
855 FORMAT(1H0,90X,F15.1)
860 CALL MIN2V(FN2I(1),DFN2(1),FN2E(1),FN2I(2),DFN2(2),FN2E(2))
      D2=D2+DD2
      IF(D2.LT.D2E) GO TO 852
      GO TO 20
      END
@FOR, IS SOLN2
      SUBROUTINE SOLN2
C      SOLVES FOR REAL PART OF REFRACTIVE INDEX AND THICKNESS OF
C      A FILM FOR MEASUREMENTS OF DELTA AND PSI
C      ER2 IS ERROR OF SOLUTION,THICK IS FILM THICKNESS,INDEX IN FN2
C      IF K=1 OR 3, FIRST(POSITIVE SIGN) SOLUTION IS USED
C      IF K=2 OR 4, SECOND(NEGATIVE SIGN) SOLUTION IS USED
      COMMON FN1,S1,C1,N,FNX(900),D(900),FN2,CRP,CRN,CRP32,CRN32,WL,
1 RP21,RN21,DEL,PSI,C2,C3,FN2I(2),DFN2(2),FN2E(2),FN2X(2),T1,T2,T3,
2 T4,D2,DELX,PSIX,ELDEL,ELPSI,DENP,FNP,DEN1,M,K,IS
      COMPLEX FNX,FN2,CRP,CRN,CRP32,CRN32,RP21,RN21,C2,C3,T1,T2,T3,T4,
1 T5,T6,RHO,RC
C      S IS USED FOR CALCULATING SPECIFIC REFRACTION
      S(XN)=(XN*XN-1.)/(XN*XN+2.)
      ATAND(X)=ATAN(X)*57.29578
      X1=FN2X(1)
      X3=FN2X(1)+DFN2(1)
      GO TO (10,20,10,20),K
10 ER1=AIMAG(T1)
   ER3=AIMAG(T3)
      GO TO 30
20 ER1=AIMAG(T2)
   ER3=AIMAG(T4)
30 DO 80 I=1,20
      X2=(X1+X3)/2.
      FN2=CMPLX(X2,-FN2X(2)*X2)
      CALL CRC
      CALL CALDX(T5,T6)
      GO TO (40,50,40,50),K
40 D2=REAL(T5)
   ER2=AIMAG(T5)
      GO TO 60
50 D2=REAL(T6)
   ER2=AIMAG(T6)
C      COMPUTE DEL AND PSI FOR FILM THICKNESS D2
60 RHO=RC(RP21,CRP32,FN2*C2*D2/WL)/RC(RN21,CRN32,FN2*C2*D2/WL)
   DELX=ATAN2(AIMAG(RHO),REAL(RHO))*57.29578-DEL
   PSIX=ATAND(CABS(RHO))-PSI
   IF(ABS(DELX).LT.ELDEL.AND. ABS(PSIX).LT.ELPSI) GO TO 100
C      HAS NOT CONVERGED TO ELDEL AND ELPSI. CHANGE LIMITS X1,X3
C      IF ER1 AND ER2 HAVE SAME SIGN,X1=X2 AND ER1=ER2,OTHERWISE
C      ER2 AND ER3 HAVE SAME SIGN,X3=X2 AND ER3=ER2

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      IF((ER1.GT.0.0 .AND. ER2.GT.0.0).OR.(ER1.LT.0.0 .AND.
1  ER2.LT.0.0)) GO TO 70
      X3=X2
      ER3=ER2
      GO TO 80
70  X1=X2
      ER1=ER2
80  CONTINUE
90  D2=1.0E30
      FN2=1.0E30
      RETURN
C  IF FILM THICKNESS D2 IS NEGATIVE,TREAT AS NO SOLUTION
100 IF(D2.LT.0.) GO TO 90
C  PRINT SOLUTION AND ERROR LIMITS
      IF(M.EQ.17 .OR. M.EQ.22) GO TO 120
      DIFN21=X2-FN1
      DIFN32=REAL(FNX(N+1))-X2
      FRACTN=DENP/(DENP+(S(X2)-S(FNP))*DEN1/(S(FN1)-S(X2)))
      WTMT=1.0E-5*D2*FRACTN/(FRACTN/DENP+(1.-FRACTN)/DEN1)
      FN2R=REAL(FN2)
      FNXR=REAL(FNX(N+1))
      FK2=-AIMAG(FN2)/REAL(FN2)
      FKX=-AIMAG(FNX(N+1))/REAL(FNX(N+1))
      PRINT 110,D2,FN2R,FK2,WTMT,DELX,PSIX,ER2,DIFN21,DIFN32,
1  FRACTN,FNXR,FKX,K
110 FORMAT(1H ,F8.1,2F9.5,1PE12.4,0P2F9.3,F12.5,3F10.5,2F9.5,I6)
      IS=2
120 RETURN
      END
@FOR, IS CRC1, CRC1
      SUBROUTINE CRC
C  CALCULATES CRP32 AND CRN32 REFLECTION COEF OF MEDIUM 2 AND 3
      COMMON FN1,S1,C1,N,FNX(900),D(900),FN2,CRP,CRN,CRP32,CRN32,WL,
1  RP21,RN21,DEL,PSI,C2,C3,FN2I(2),DFN2(2),FN2E(2),FN2X(2),T1,T2,T3,
2  T4,D2,DELX,PSIX,ERDEL,ERPSI,DENP,FNP,DEN1
      COMPLEX FNX,FN2,CRP,CRN,CRP32,CRN32,RP21,RN21,C2,C3,T1,T2,T3,T4
      COMPLEX RC,RP32,RN32
      SRC(A,B)=(A-B)/(A+B)
      X=FN1*S1
      C2=CSQRT(1.-(X/FN2)**2)
      C3=CSQRT(1.-(X/FNX(3))**2)
      RP21=SRC(FN2*C1,FN1*C2)
      RN21=SRC(FN1*C1,FN2*C2)
      IF(N.EQ.2) GO TO 10
      RP32=SRC(FNX(3)*C2,FN2*C3)
      RN32=SRC(FN2*C2,FNX(3)*C3)
      CRP32=RC(RP32,CRP,FNX(3)*C3*D(3)/WL)
      CRN32=RC(RN32,CRN,FNX(3)*C3*D(3)/WL)
      RETURN
10  CRP32=SRC(FNX(3)*C2,FN2*C3)
      CRN32=SRC(FN2*C2,FNX(3)*C3)
      RETURN
      END
@FOR, IS RCX, RCX
      COMPLEX FUNCTION RC(R21,CR32,Q )
C  RC=REFLECTION COEFFICIENT INCLUDING EFFECT OF UNDERLYING LAYERS
C  FOLLOWING CARD IS REQUIRED FOR FORTRAN V ONLY
      COMPLEX CEXP,CLOG,CSQRT
      COMPLEX R21,CR32,Q ,T
      T=CEXP((0.,-12.56637)*Q)
C  Q=N2*COS(PHI2)*D/WL (0.,-12.56637)=-4*PI*J
      RC=(R21+CR32*T)/(1.+R21*CR32*T)

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      RETURN
    END
  @FOR, IS CALD, CALD
    SUBROUTINE CALDX(D2C1,D2C2)
  C   FOLLOWING CARD IS REQUIRED FOR FORTRAN V ONLY
    COMPLEX CEXP,CLOG,CSQRT
  C   CALCULATES FILM THICKNESS AND ERROR TERMS
    COMMON FN1,S1,C1,N,FNX(900),D(900),FN2,CRP,CRN,CRP32,CRN32,WL,
  1  RP21,RN21,DEL,PSI,C2,C3,FN2I(2),DFN2(2),FN2E(2),FN2X(2),T1,T2,T3,
  2  T4,D2,DELDX,PSIDX,ERDEL,ERPSI,DENP,FNP,DEN1,M,K
    COMPLEX FNX,FN2,CRP,CRN,CRP32,CRN32,RP21,RN21,C2,C3,T1,T2,T3,T4
    COMPLEX E,B,C,Y1,Y2,D2C1,D2C2,RHO,T5,T6
    RHO=SIN(PSI/57.29578)/COS(PSI/57.29578)*CEXP((0.,1.)*DEL/57.29578)
  C   Y=EXP(-2 J DEL2) LET E***2+BY+C=0 Y1,Y2 ARE TWO SOLUTIONS
    E=RHO*RP21*CRP32*CRN32-RN21*CRP32*CRN32
    B=RHO*(CRN32*RP21*RN21*CRP32)-CRP32*RP21*RN21*CRN32
    C=RHO*RN21*RP21
    T5=CSQRT(B**2-4.*E*C)
    GO TO (20,20,10,10),K
  C   MAKE IMAGINARY PART OF SQUARE ROOT POSITIVE
  10 IF(AIMAG(T5).LT.0.) T5=-T5
  20 Y1=(-B+T5)/2./E
    Y2=(-B-T5)/2./E
    T5=CLOG(Y1)
    T6=CLOG(Y2)
    D2C1=WL*T5/(0.,-12.56637)/FN2/C2
    D2C2=WL*T6/(0.,-12.56637)/FN2/C2
    RETURN
  END
  @FOR, IS MIN2, MIN2
    SUBROUTINE MIN2V(XI,DX,XF,YI,DY,YF)
  C   USES FUNCTION FUNC(X,Y) WHICH MUST BE INCLUDED. DETERMINES AND PRINTS
  C   VALUES OF X BETWEEN XI AND XF AND VALUES OF Y BETWEEN YI AND YF THAT
  C   MINIMIZE FUNC. WILL FIND MULTIPLE MINIMUMS IF THEY ARE SEPARATED
  C   BY MORE THAN DX AND DY
    DIMENSION F(50,50)
    COMMON FN1,S1,C1,N,FNX(900),D(900),FN2,CRP,CRN,CRP32,CRN32,WL,
  1  RP21,RN21,DEL,PSI,C2,C3,FN2I(2),DFN2(2),FN2E(2),FN2X(2),T1,T2,T3,
  2  T4,D2,DELDX,PSIDX,ERDEL,ERPSI,DENP,FNP,DEN1,M,K,IS,RHO
    COMPLEX FNX,FN2,CRP,CRN,CRP32,CRN32,RP21,RN21,C2,C3,T1,T2,T3,T4
    COMPLEX RC,RHO
  C   COMPUTE NUMBER OF VALUES OF X AND Y FOR RANGES XI-DX TO XF+DX
  C   AND YI-DY TO YF+DY.
    NX=(1.000001*XF-XI)/DX+3
    NY=(1.000001*YF-YI)/DY+3
    IF(NX.GT.50) PRINT 10,DX
  10 FORMAT('OINCREMENT OF X,'E12.5,' IS TOO SMALL')
    IF(NY.GT.50) PRINT 20,DY
  20 FORMAT('OINCREMENT OF Y,'E12.5,' IS TOO SMALL')
  C   COMPUTE INITIAL VALUE OF X
    X=XI-DX
  C   COMPUTE TABLE F OF FUNCTION FUNC
    DO 40 I=1,NX
      Y=YI-DY
      DO 30 J=1,NY
        F(I,J)=FUNC(X,Y)
  C*****DIAGNOSTIC PRINTING*****
  C   PRINT 35,I,J,F(I,J)
  30 Y=Y+DY
  35 FORMAT(2I5,E20.7)
  40 X=X+DX
    NX1=NX-1

```

```

        NY1=NY-1
        DO 910 I=2,NX1
        DO 900 J=2,NY1
C       SEARCH FOR MINIMUMS OF F(VALUES LESS THAN ALL 8 SURROUNDING VALUES)
          IF(F(I,J).LT.F(I-1,J-1).AND. F(I,J).LT.F(I-1,J) .AND.
1         F(I,J).LT.F(I-1,J+1) .AND. F(I,J).LT.F(I,J-1) .AND.
2         F(I,J).LT.F(I,J+1) .AND. F(I,J).LT.F(I+1,J-1)
3         .AND. F(I,J).LT.F(I+1,J) .AND.
4         F(I,J).LT.F(I+1,J+1))GO TO 50
          GO TO 900
50      XMIN=XI+(I-2)*DX
        YMIN=YI+(J-2)*DY
        FMIN=F(I,J)
C       A MINIMUM FMIN OCCURS NEAR POINT I,J AT XMIN-DX TO XMIN+DX AND
C       YMIN-DY TO YMIN+DY,
C       SUBDIVIDE RANGE TO LOCATE MINIMUM.
          XD=DX/2
          YD=DY/2
C       SUBDIVIDE RANGE 10 TIMES
          DO 550 K=1,10
            F13=FUNC(XMIN-XD,YMIN-YD)
            F14=FUNC(XMIN,YMIN-YD)
            IF(F13.LT.FMIN) GO TO 110
            IF(F14.LT.FMIN) GO TO 120
C           F14 GT FMIN
105          F15=FUNC(XMIN+XD,YMIN-YD)
            IF(F15.LT.FMIN) GO TO 130
C           F15 GT FMIN
107          F18=FUNC(XMIN+XD,YMIN)
            IF(F18.LT.FMIN) GO TO 140
            F22=FUNC(XMIN+XD,YMIN+YD)
            IF(F22.LT.FMIN) GO TO 150
C           F22 GT FMIN
            F21=FUNC(XMIN,YMIN+YD)
            IF(F21.LT.FMIN) GO TO 160
C           F21 GT FMIN
            F20=FUNC(XMIN-XD,YMIN+YD)
            IF(F20.LT.FMIN) GO TO 170
            F17=FUNC(XMIN-XD,YMIN)
            IF(F17.LT.FMIN) GO TO 180
C           FMIN LT SURROUNDINGS
            GO TO 500
110         IF(F14.LT.F13) GO TO 120
C           F13 LT F14 AND FMIN
            F17=FUNC(XMIN-XD,YMIN)
C           IF F17 LT F13, CONTINUE SCAN WITH F15
            IF(F17.LT.F13) GO TO 105
C           F13 LT F14,FMIN,F17
            F12=FUNC(XMIN-2*XD,YMIN-YD)
            IF(F12.LT.F13) GO TO 190
            F10=FUNC(XMIN-XD,YMIN-2*YD)
            IF(F10.LT.F13) GO TO 200
C           F13 IS NEW MINIMUM
            FMIN=F13
            XMIN=XMIN-XD
            YMIN=YMIN-YD
            GO TO 500
C           F14 LT FMIN,F13
120          F15=FUNC(XMIN+XD,YMIN-YD)
            IF(F15.LT.F14) GO TO 130
            F11=FUNC(XMIN+XD,YMIN-2*YD)
            IF(F11.LT.F14) GO TO 210

```

```

      F10=FUNC(XMIN-XD,YMIN-2*YD)
      IF(F10.LT.F14) GO TO 200
      F17=FUNC(XMIN-XD,YMIN)
      IF(F17.LT.F14) GO TO 107
      F18=FUNC(XMIN+XD,YMIN)
      IF(F18.LT.F14) GO TO 140
C      F14 IS NEW MINIMUM
      FMIN=F14
      YMIN=YMIN-YD
      GO TO 500
C      F15 LT FMIN ,F14
130      F11=FUNC(XMIN+XD,YMIN-2*YD)
      IF(F11.LT.F15) GO TO 210
      F18=FUNC(XMIN+XD,YMIN)
      IF(F18.LT.F15) GO TO 140
      F16=FUNC(XMIN+2*XD,YMIN-YD)
      IF(F16.LT.F15) GO TO 220
C      F15 IS NEW MINIMUM
      FMIN=F15
      XMIN=XMIN+XD
      YMIN=YMIN-YD
      GO TO 500
C      F18 LT FMIN,F15,F14
140      F16=FUNC(XMIN+2*XD,YMIN-YD)
      IF(F16.LT.F18) GO TO 220
      F22=FUNC(XMIN+XD,YMIN+YD)
      IF(F22.LT.F18) GO TO 150
      F21=FUNC(XMIN,YMIN+YD)
      IF(F21.LT.F18) GO TO 160
      F23=FUNC(XMIN+2*XD,YMIN+YD)
      IF(F23.LT.F18) GO TO 230
C      F18 IS NEW MINIMUM
      FMIN=F18
      XMIN=XMIN+XD
      GO TO 500
C      F22 LT FMIN,F18
150      F21=FUNC(XMIN,YMIN+YD)
      IF(F21.LT.F22) GO TO 160
      F23=FUNC(XMIN+2*XD,YMIN+YD)
      IF(F23.LT.F22) GO TO 230
      F25=FUNC(XMIN+XD,YMIN+2*XD)
      IF(F25.LT.F22) GO TO 240
C      F22 IS NEW MINIMUM
      FMIN=F22
      XMIN=XMIN+XD
      YMIN=YMIN+YD
      GO TO 500
C      F21 LT FMIN,F22,F18
160      F25=FUNC(XMIN+XD,YMIN+2*XD)
      IF(F25.LT.F21) GO TO 240
      F20=FUNC(XMIN-XD,YMIN+YD)
      IF(F20.LT.F21) GO TO 170
      F17=FUNC(XMIN-XD,YMIN)
      IF(F17.LT.F21) GO TO 180
      F24=FUNC(XMIN-XD,YMIN+2*YD)
      IF(F24.LT.F21) GO TO 250
C      F21 IS NEW MINIMUM
      FMIN=F21
      YMIN=YMIN+YD
      GO TO 500
C      F20 LT FMIN,F21
170      F17=FUNC(XMIN-XD,YMIN)

```

```

        IF(F17.LT.F20) GO TO 180
        F24=FUNC(XMIN-XD,YMIN+2*YD)
        IF(F24.LT.F20) GO TO 250
        F19=FUNC(XMIN-2*XD,YMIN+YD)
        IF(F19.LT.F20) GO TO 260
C      F20 IS NEW MINIMUM
        FMIN=F20
        XMIN=XMIN-XD
        YMIN=YMIN+YD
        GO TO 500
C      F17 LT FMIN F20,F21,F13,F14
180      F12=FUNC(XMIN-2*XD,YMIN-YD)
        IF(F12.LT.F17) GO TO 190
        F19=FUNC(XMIN-2*XD,YMIN+YD)
        IF(F19.LT.F17) GO TO 260
C      F17 IS NEW MINIMUM
        FMIN=F17
        XMIN=XMIN-XD
        GO TO 500
C      F12 LT F13,FMIN,F17
190      F10=FUNC(XMIN-XD,YMIN-2*YD)
        IF(F10.LT.F12) GO TO 200
        FMIN=F12
        XMIN=XMIN-2*XD
        YMIN=YMIN-YD
192      FX=FUNC(XMIN-XD,YMIN-YD)
        IF(FMIN.GT.FX) GO TO 194
        FX=FUNC(XMIN-XD,YMIN)
        IF(FMIN.GT.FX) GO TO 196
        FX=FUNC(XMIN-XD,YMIN+YD)
        IF(FMIN.GT.FX) GO TO 198
        GO TO 500
194      YMIN=YMIN-YD
196      XMIN=XMIN-XD
        FMIN=FX
        GO TO 300
198      YMIN=YMIN+YD
        GO TO 196
C      F10 LT F13,F14,F12,FMIN
200      FMIN=F10
C      CHECK TO SEE THAT F10 IS NEW MINIMUM
        XMIN=XMIN-XD
        YMIN=YMIN-2*YD
202      FX=FUNC(XMIN-XD,YMIN-YD)
        IF(FMIN.GT.FX) GO TO 204
        FX=FUNC(XMIN,YMIN-YD)
        IF(FMIN.GT.FX) GO TO 206
        FX=FUNC(XMIN+XD,YMIN-YD)
        IF(FMIN.GT.FX) GO TO 208
        GO TO 500
204      XMIN=XMIN-XD
206      YMIN=YMIN-YD
        FMIN=FX
        GO TO 300
208      XMIN=XMIN+XD
        GO TO 206
C      F11 LT F14,F15
210      F18=FUNC(XMIN+XD,YMIN)
        IF(F18.LT.F11) GO TO 140
        F16=FUNC(XMIN+2*XD,YMIN-YD)
        IF(F16.LT.F11) GO TO 220
        FMIN=F11

```

```

      XMIN=XMIN+XD
      YMIN=YMIN-2*YD
      GO TO 202
C     F16 LT F15,F11,F18
220    FMIN=F16
      XMIN=XMIN+2*XD
      YMIN=YMIN-YD
222    FX=FUNC(XMIN+XD,YMIN-YD)
      IF(FMIN.GT.FX) GO TO 224
      FX=FUNC(XMIN+XD,YMIN)
      IF(FMIN.GT.FX) GO TO 226
      FX=FUNC(XMIN+XD,YMIN+YD)
      IF(FMIN.GT.FX) GO TO 228
      GO TO 500
224    YMIN=YMIN-YD
226    XMIN=XMIN+XD
      FMIN=FX
      GO TO 300
228    YMIN=YMIN+YD
      GO TO 226
C     F23 LT F18,F22,FMIN
230    F25=FUNC(XMIN+XD,YMIN+2*XD)
      IF(F25.LT.F23) GO TO 240
      FMIN=F23
      XMIN=XMIN+2*XD
      YMIN=YMIN+YD
      GO TO 222
C     F25 LT F21,F22,F23,FMIN
240    FMIN=F25
      XMIN=XMIN+XD
      YMIN=YMIN+2*YD GO
242    FX=FUNC(XMIN-XD,YMIN+YD)
      IF(FMIN.GT.FX) GO TO 244
      FX=FUNC(XMIN,YMIN+YD)
      IF(FMIN.GT.FX) GO TO 226
      FX=FUNC(XMIN+XD,YMIN+YD)
      IF(FMIN.GT.FX) GO TO 248
      GO TO 500
244    XMIN=XMIN-XD
246    YMIN=YMIN+YD
      FMIN=FX
      GO TO 300
248    XMIN=XMIN+XD
      GO TO 246
C     F24 LT F21,F20,F17,FMIN
250    F19=FUNC(XMIN-2*XD,YMIN+YD)
      IF(F19.LT.F24) GO TO 260
      FMIN=F24
      XMIN=XMIN-XD
      YMIN=YMIN+2*YD
      GO TO 242
C     F19 LT F20,F17,FMIN
260    F17=FUNC(XMIN-XD,YMIN)
      IF(F17.LT.F19) GO TO 180
      FMIN=F19
      XMIN=XMIN-2*XD
      YMIN=YMIN+YD
      GO TO 192
C     FOLLOW MINIMUM FOR 5 STEPS
300    DO 400 KK=1,5
      FX=FUNC(XMIN-XD,YMIN-YD)
      IF(FX.LT.FMIN) GO TO 310

```

```

      FX=FUNC(XMIN-XD,YMIN)
      IF(FX.LT.FMIN) GO TO 320
      FX=FUNC(XMIN-XD,YMIN+YD)
      IF(FX.LT.FMIN) GO TO 330
      FX=FUNC(XMIN,YMIN-YD)
      IF(FX.LT.FMIN) GO TO 340
      FX=FUNC(XMIN,YMIN+YD)
      IF(FX.LT.FMIN) GO TO 350
      FX=FUNC(XMIN+XD,YMIN-YD)
      IF(FX.LT.FMIN) GO TO 360
      FX=FUNC(XMIN+XD,YMIN)
      IF(FX.LT.FMIN) GO TO 370
      FX=FUNC(XMIN+XD,YMIN+XD)
      IF(FX.LT.FMIN) GO TO 380
      GO TO 500
310      YMIN=YMIN-YD
320      XMIN=XMIN-XD
      GO TO 400
330      YMIN=YMIN+YD
      GO TO 320
340      YMIN=YMIN-YD
      GO TO 400
350      YMIN=YMIN+YD
      GO TO 400
360      YMIN=YMIN-YD
370      XMIN=XMIN+XD
      GO TO 400
380      YMIN=YMIN+YD
      GO TO 370
400      FMIN=FX
C          A MINIMUM IS NOT FOUND IN 5 STEPS
      GO TO 600
500      XD=XD/2
      YD=YD/2
550      CONTINUE
C          NEW MINIMUM IS FOUND
      GO TO 700
560      FORMAT(5E15.6,3I5/(7F15.6))
600      PRINT 610,K,FMIN,XMIN,YMIN,XD,YD
610      FORMAT('0 ITERATION NUMBER',I3,' FAILED FOR MINIMUM',E12.5,' AT X
1=,E12.5,' Y=',E12.5,' RANGES =',2E12.5)
C*****PRINT VALUES AT MINIMUM
700      FN2=CMPLX(XMIN,-XMIN*YMIN)
      T1=RC(RP21,CRP32,FN2*C2*D2/WL)/RC(RN21,CRN32,FN2*C2*D2/WL)
      DDEL=ATAN2(AIMAG(T1),REAL(T1))*57.29578-DEL
      DPSI=ATAN(ABS(T1))*57.29578-PSI
      XD=2*XD
      YD=2*YD
      PRINT 800, XMIN,YMIN,XD,YD,FMIN,DDEL,DPSI
800      FORMAT(' 5F15.5,2F10.3)
900      CONTINUE
910      CONTINUE
      RETURN
      END

```

@FOR, IS FUNC

```

      FUNCTION FUNC(FRN,FK)
C          COMPUTES VALUES OF DELTA AND PSI, DELC AND PSIC, FOR A FILM
C          OF N=FRN,KAPPA=FK, AND THICKNESS=D2 AND ERROR TERM,FUNC
      COMMON FN1,S1,C1,N,FNX(900),D(900),FN2,CRP,CRN,CRP32,CRN32,WL,
1 RP21,RN21,DEL,PSI,C2,C3,FN2I(2),DFN2(2),FN2E(2),FN2X(2),T1,T2,T3,
2 T4,D2,DELDX,PSIDX, ERDEL,ERPSI, DENP,FNP,DEN1,MX,K,IS,RHO
      COMPLEX FNX,FN2,CRP,CRN,CRP32,CRN32,RP21,RN21,C2,C3,T1,T2,T3,T4

```

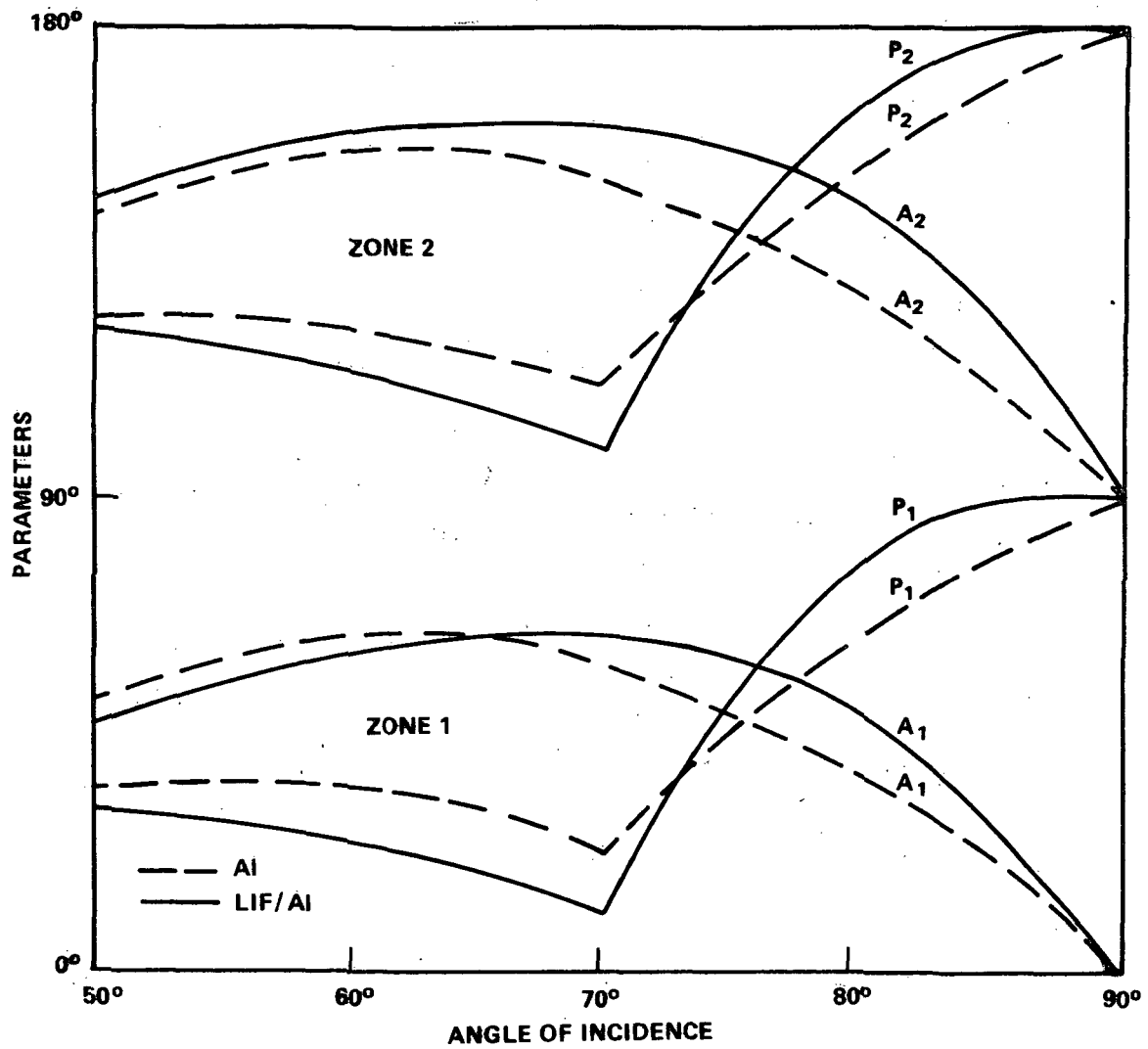
COMPLEX RC,RHO  
FN2=CMPLX(FRN,-FRN\*FK)  
CALL CRC  
FUNC=ABS(RC(RP21,CRP32, FN2\*C2\*D2/WL)/RC(RH21,CPN32, FN2\*C2\*D2/WL))  
1 -RHO)  
RETURN  
END

@PRT, T TPF \$.  
@MAP, IL A,B  
LIB SYS\*MSFC \$.  
@XQT, B  
BLANK CARD  
DATA CARDS  
@FIN

## **APPENDIX B**

**P AND A VALUES AS FUNCTIONS OF INCIDENCE  
FOR LIF/AL AND AL MIRRORS FOR ZONES 1 AND 2**





## APPENDIX C

### MEASURABLE ELLIPSOMETRIC PARAMETERS FOR SEVERAL OPAQUE REFLECTORS

# A. P and A Values for Several Types of Mirrors

MIRROR	A	P
Au	54.23	4.25
	150.90	95.75
Al	150.25	74.00
	58.25	163.25
Lif/Al	144.25	8.93
	41.63	99.30
Al/Au	153.10	8.93
	51.15	98.70
DC-704 Oil/Au	146.25	3.50
	55.00	92.13
Unknown Contaminant/Lif/Al	149.45	85.85
	51.50	177.77

B. P and A Values Versus Angle of Incidence and  $1/4 \lambda$   
Plate Settings of Al Mirror

Angle of Incidence, degrees	$1/4 \lambda$ Plate setting, degrees	A	P
70	-45	53.42 147.25	76.50 163.75
70	+45	57.17 147.50	22.67 111.42
60	-45	56.30 149.20	63.62 153.87
60	+45	50.90 150.75	30.40 121.60
55	-45	57.30 148.70	60.40 150.12
55	+45	49.12 154.45	34.30 124.75

## APPENDIX D

### CALCULATION OF FILM THICKNESS AS A FUNCTION OF SMALL DELTA FOR A TRANSPARENT FILM ON SILICON

Calculation of film thickness as a function of  $\delta$  (small delta) for a transparent film on silicon [ 3] where

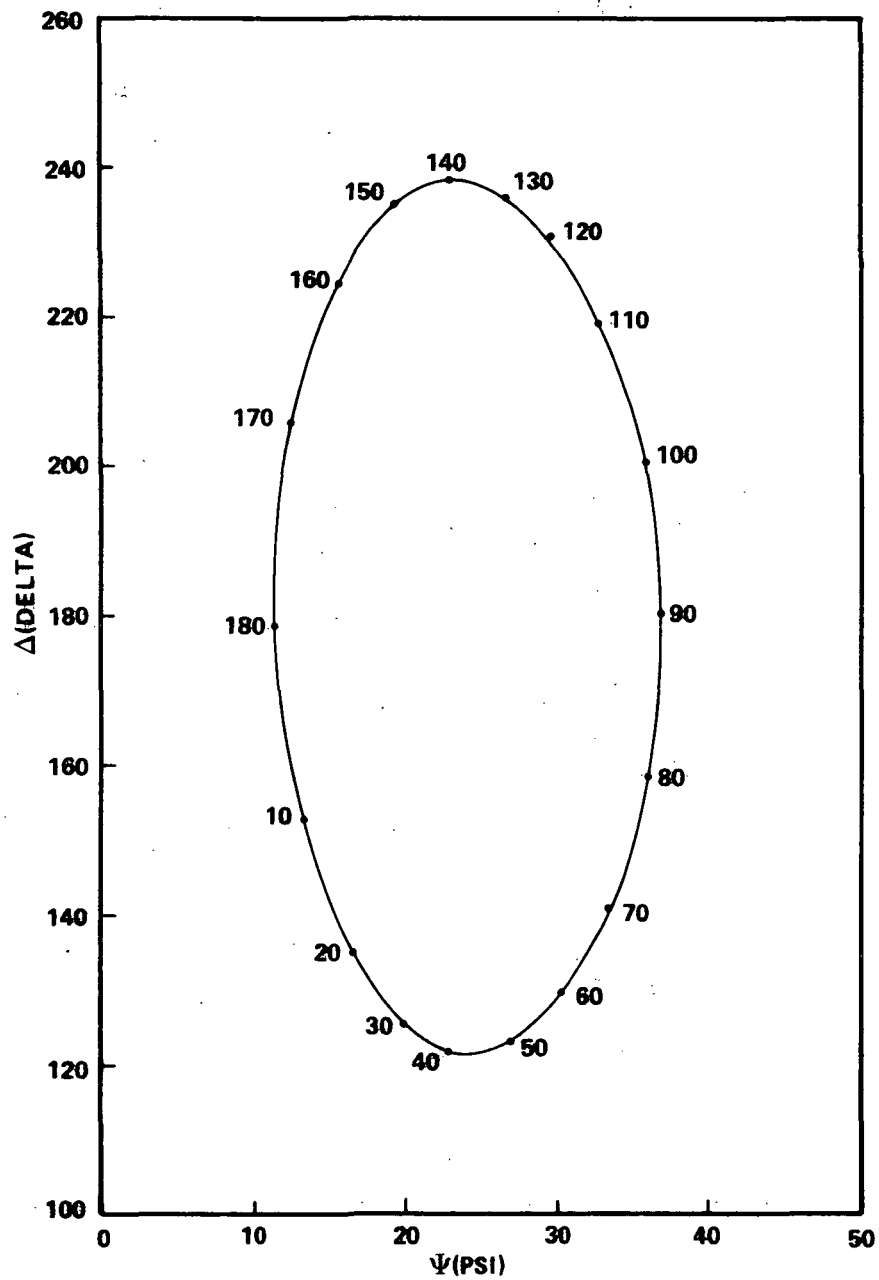
$$\delta \text{ (real)} = \frac{360d}{\lambda} \left[ \left( N_1^2 - K_1^2 - \sin^2 \Theta \right)^2 + 4N_1^2 K_1^2 \right]^{\frac{1}{4}} \times \cos \left[ \frac{1}{2} \tan^{-1} \left( \frac{-2N_1 K_1}{N_1^2 - K_1^2 - \sin^2 \Theta} \right) \right]$$

Index of refraction is 1-10.

Small delta ( $\delta$ )	Thickness (d), nm
0.0	0.000
0.05	0.01925
0.25	0.09627
0.50	0.1925
2.50	0.9627
5.00	1.9254
7.50	2.888
10.0	3.85
20.0	7.70
30.0	11.50
40.0	15.40
50.0	19.25
60.0	23.10
70.0	26.95
80.0	30.80
90.0	34.658
100.0	38.508
110.0	42.35
120.0	46.21
130.0	50.06
140.0	53.9125
150.0	57.76
160.0	61.6143
170.0	65.46
180.0	69.316

## APPENDIX E

### THICKNESS OF A TRANSPARENT FILM ON AN OPAQUE SUBSTRATE AS A FUNCTION OF THE MEASURABLE ELLIPSOMETRIC PARAMETERS $\Delta$ AND $\psi$





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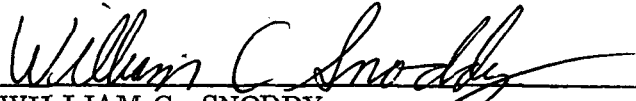
## APPROVAL


### THE GAERTNER L119 ELLIPSOMETER AND ITS USE IN THE MEASUREMENT OF THIN FILMS

By Michael Linkous

The information in this report has been reviewed for security classification. Review of any information concerning Department of Defense or Atomic Energy Commission programs has been made by the MSFC Security Classification Officer. This report, in its entirety, has been determined to be unclassified.

This document has also been reviewed and approved for technical accuracy.

  
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